



DOCKET NO: 264197US0PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :  
SHINSUKE SADAMITSU, ET AL. : EXAMINER: M.A. WILCZEWSKI  
SERIAL NO: 10/519,837 :  
FILED: JULY 5, 2005 : GROUP ART UNIT: 2822  
FOR: HIGH-RESISTANCE SILICON WAFER AND ITS MANUFACTURING  
METHOD

AMENDMENT AND REQUEST FOR RECONSIDERATION

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Responsive to the Office Action dated December 13, 2006, Applicants respectfully request reconsideration of the above-identified application in view of the following amendments and remarks:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

A discussion of the **Support for the Amendments** begins on page 6 of this paper.

**Remarks** begin on page 7 of this paper.